

03500.010530.5

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Kiyofumi SAKAGUCHI, et al.) : Examiner: George R. Fourson, III
Appln. No.: 10/085,046) : Group Art Unit: 2823
Filed: March 1, 2002) : Confirmation No.: 7805
For: PROCESS FOR PRODUCTION OF) :
SEMICONDUCTOR SUBSTRATE : November 7, 2006

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

FIFTH INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents, other than U.S. patent documents, are enclosed.

REMARKS

An English-language Abstract for JP-A 60-196955 was obtained from a commercial database and is also enclosed.

ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /GF/

FORMAL MATTERS

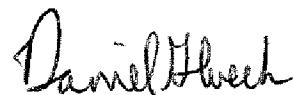
No fee is believed due; however, any fee required in connection with this paper should be charged to Deposit Account No. 06-1205.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
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Registration No. 37,838

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| FORM PTO 1449 (modified) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary) Dated Submitted to USPTO: November 7, 2006 | | | ATTY DOCKET NO. 03500.010530.5 | | APPLICATION NO 10/085,046 | | |
|---|---------------------|---|--|------------|-------------------------------------|----------------------------|--|
| | | | APPLICANT Kiyofumi SAKAGUCHI, et al. | | | | |
| | | | FILING DATE March 1, 2002 | | GROUP 2823 | | |
| | | | U.S. PATENT DOCUMENTS | | | | |
| *EXAMINER INITIAL | DOCUMENT NUMBER | DATE | NAME | CLASS | SUBCLASS | FILING DATE IF APPROPRIATE | |
| | 5,175,610 | 12/29/1992 | Kobayashi | 257 | 676 | | |
| | 4,670,763 | 06/02/1987 | Ovshinsky, et al. | 357 | 4 | | |
| | 4,555,586 | 11/26/1985 | Guha, et al. | 136 | 259 | | |
| | 4,426,657 | 01/17/1984 | Abiru, et al. | 357 | 29 | | |
| | 4,064,521 | 12/20/1977 | Carlson | 357 | 2 | | |
| DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION YES/NO/ OR ABSTRACT | | |
| | 60-196955 | 10/05/1985 | Japan | | | Abstract | |
| | 0 469 630 A2 | 02/05/1992 | Europe | | | | |
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| OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.) | | | | | | | |
| | | T. Yasumatsu, et al., "Ultrathin Si Films Grown Epitaxially on Porous Silicon", Applied Surface Science, Vols. 48 & 49, pp. 414-418 (1991) | | | | | |
| | | Handbook of Thin Film Technology, 5-17 to 5-25 (Eds., L. I. Maissel and R. Glang 1970) | | | | | |
| | | Robert F. Pierret, Semiconductor Device Fundamentals, pp. 347-368 (date unknown) | | | | | |
| EXAMINER | /George Fourson/ | | DATE CONSIDERED | 02/25/2008 | | | |

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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| FOREIGN PATENT DOCUMENTS | | | | | | | |
| | | DOCUMENT NUMBER | DATE | COUNTRY | CLASS | SUBCLASS | TRANSLATION YES/NO/ OR ABSTRACT |
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| | | W. Kern & V. Ban, Thin Film Processes, Chemical Vapor Deposition of Inorganic Thin Films, pp. 257-331 (1978) | | | | | |
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| | | R. Pierret, Modular Series on Solid State Devices, Vol. 4, pp. 59-80 (1983) | | | | | |
| EXAMINER | | /George Fourson/ | | DATE CONSIDERED | | 03/19/2008 | |

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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